

The Abdus Salam International Centre for Theoretical Physics



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Workshop on Biomedical Applications of High Energy Ion Beams

Co-sponsored by: ICGEB and University of Surrey

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Venue: Adriatico Guest House Giambiagi Lecture Hall ICTP, Trieste, Italy

Using Ion Beams to Analyse Biomedical Materials on the Micro and Nano Scale

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Photonics applications





CIBA

The waveguides fabricated using pbeam writing have smooth and vertical sidewalls, and exhibit low loss



CIBA Photonics applications



Free standing waveguides and optical components:





Test **waveguide structures** showing the side wall smoothness and orthogonality that can be achieved using p-beam writing. These structures were fabricated in a 30 µm layer of SU-8 spin coated on a silicon wafer.

CIBA Biochip applications





A series of reservoirs are connected by 100nm wide channels: When an electric field is applied along the channels, the DNA is stretched through the nanochannels at a rate which depends on the size and unfolding characteristics of the DNA.

DNA – Protein sorting using entropic trapping







DNA – protein ratchet sorter: Using a combination of Brownian motion and Electrokinetic force, large molecules drift vertically through the obstacles, whereas the smaller molecules are ratcheted to the right.









Imprinting and molding

Proton beam writing is as fast (or maybe faster than) e-beam writing. However these techniques are serial techniques (writing structures one at a time).

If we use p-beam writing to make stamps and molds for imprinting, then we can mass produce devices.....











IMPRINTING

- A structure is made in PMMA using proton beam writing.
- The structure is electroplated to make a metallic (nickel) negative – eg 100nm nickel stamp, 2 microns deep.

•The PMMA is chemically removed

An imprint of the nickel stamp is made in polymer using hot embossing – heating the polymer up to its plastic temperature and pressing the stamp into the hot polymer.







MOLDING

- A structure is made in PMMA using proton beam writing.
- The structure is electroplated to make a metallic (nickel) negative -
- •The PMMA is chemically removed leaving a high quality 3D stamp.



PDMS is poured into the mold, allowed to set, and released. The structure can be bonded onto glass eg to form a biochip cell sorter.....





SEM image of a prototype inter-digitated nano-biosensor structure with 85 nm gaps, using proton beam writing and metal lift-off.



Lithography of high spatial density biosensor structures with sub-100 spacing by MeV proton beam writing with minimal proximity effects. Nanotechnology 15 (2003) 223-226. HJ Whitlow, ML Ng, V Auzelyte, I Maximov, L Montelius, JA van Kan, AA Bettiol and F Watt.









Cells align on ridge structures that are narrower than the natural cell width.... Tissue engineering applications

CIBA Cell biomechanical studies



Human Red Blood Cell behavior in PDMS microchannels:

Biomechanical properties

Biconcave shape observed under optical microscope









Red blood cell shape and its viscoelastic transporting model



Viscoelastic behavior of a red blood cell through micro capillary



Channel Design



Four kinds of PDMS channels (made from a metallic mold fabricated using p-beam writing and electroplating) were designed to study the cell deformability:
8µm(w) x 2µm: no deformation
6µm(w) x 2µm: slightly stretched
4µm(w) x 2µm: notable stretching
2µm(w) x 2µm: maximal stretch in microchannels;
52µm(L): sufficient traveling distance to monitor single cell movement.







Experimental set up and sample preparation



Preparation of blood sample:

Drawing fresh blood in micro liters from healthy adult;

Diluting with 1XPBS (1mM Phosphate Buffered Saline) to 3~5%;

Vibrating mixing for 1 min.







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6μm(w) x 2μm: slightly stretched







4µm(w)x 2µm: notable stretching







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Captured pictures showing cell deformation at capillary entrance







Conclusions:

Proton beam writing: Great potential for 3D fabrication down to the nano-level....10nm and below: Great potential for biochips: Integrated microfluidics + photonics, tissue engineering substrates.....imprinting for mass production....

But: we still need further technological developments:

No commercial instrument exists as yet.....

• We need user-friendly instrumentation, operation + easy maintenance

• Improvements in proton ion source, aperture design, lens systems, target stage stability, beam control software....

Small 'footprint'.....





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Silicon micro-dragon:

Resonant cavities written in porous silicon, patterned laterally using proton beam writing and vertically using alternating etch currents.